

**City University of Hong Kong  
Course Syllabus**

**offered by Department of Mechanical and Biomedical Engineering  
with effect from Semester A 2017/18**

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**Part I Course Overview**

**Course Title:** Electron Microscopy

**Course Code:** MBE8106

**Course Duration:** One Semester

**Credit Units:** 3

**Level:** R8

**Medium of Instruction:** English

**Medium of Assessment:** English

**Prerequisites :**  
(Course Code and Title) Nil

**Precursors:**  
(Course Code and Title) Nil

**Equivalent Courses:**  
(Course Code and Title) MBE6119 Electron Microscopy

**Exclusive Courses:**  
(Course Code and Title) Nil

## Part II Course Details

### 1. Abstract

This course focuses on theories and applications of modern electron microscopy including Scanning Electron Microscopy (SEM), Transmission Electron Microscopy (TEM) and X-Ray Energy Dispersive Spectroscopy. The lectures cover basic electron optics, electron-beam and specimen interactions, electron diffraction, advanced electron imaging techniques and image interpretation, vacuum system and instrumentations, qualitative and quantitative X-ray microanalysis. The theoretical understanding gained by students will help them understand and interpret experimental data as well as perform electron microscopy experiments. Hands-on experience is also emphasized, which includes sample preparation techniques and use electron microscope(s).

### 2. Course Intended Learning Outcomes (CILOs)

| No. | CILOs   | Weighting<br>(if applicable) | Discovery-enriched curriculum related learning outcomes (please tick where appropriate) |    |    |
|-----|---|------------------------------|---|----|----|
|     |   |                              | A1  | A2 | A3 |
| 1.  | Describe the theory and applications of electron microscopy and spectroscopy techniques (SEM/TEM/EDS) |                              | √   |    |    |
| 2.  | Explain the SEM/TEM/EDS principles and the basic instrumentation and hardware                         |                              |   | √  |    |
| 3.  | Apply SEM/TEM/EDS for imaging, diffraction and spectroscopy experiments and data analysis             |                              |   |    | √  |
|     |   | 100%                         |   |    |    |

A1: Attitude

*Develop an attitude of discovery/innovation/creativity, as demonstrated by students possessing a strong sense of curiosity, asking questions actively, challenging assumptions or engaging in inquiry together with teachers.*

A2: Ability

*Develop the ability/skill needed to discover/innovate/create, as demonstrated by students possessing critical thinking skills to assess ideas, acquiring research skills, synthesizing knowledge across disciplines or applying academic knowledge to self-life problems.*

A3: Accomplishments

*Demonstrate accomplishment of discovery/innovation/creativity through producing /constructing creative works/new artefacts, effective solutions to real-life problems or new processes.*

### 3. Teaching and Learning Activities (TLAs)

| TLA        | Brief Description  | CILO No. |   |   |   | Hours/week (if applicable)     |
|------------|--|----------|---|---|---|--------------------------------|
|            |  | 1        | 2 | 3 | 4 |                                |
| Lecture    | lectures on the topics of the keyword syllabus; total 26 hours | √        | √ | √ |   | 2 hours per week               |
| Tutorial   | tutorial classes; total 6.5 hours                              | √        | √ |   |   | 0.5 hour per week              |
| Laboratory | lab experiments; total 9 hours                                 |          |   | √ |   | 3 lab sessions of 3 hours each |

### 4. Assessment Tasks/Activities (ATs)

| Assessment Tasks/Activities          | CILO No. |   |   |   | Weighting | Remarks                  |
|--------------------------------------|----------|---|---|---|-----------|--------------------------|
|                                      | 1        | 2 | 3 | 4 |           |                          |
| Continuous Assessment: 50%           |          |   |   |   |           |                          |
| Test                                 | √        | √ |   |   | 20%       | In-class test (mid-term) |
| Laboratory                           |          |   | √ |   | 30%       | Lab reports              |
| Examination: 50% (duration: 2 hours) |          |   |   |   |           |                          |
|                                      |          |   |   |   | 100%      |                          |

**For a student to pass the course, at least 30% of the maximum mark for both coursework and examination should be obtained.**

## 5. Assessment Rubrics

| Assessment Task | Criterion   | Excellent<br>(A+, A, A-) | Good<br>(B+, B, B-) | Fair<br>(C+, C, C-) | Marginal<br>(D) | Failure<br>(F)                    |
|-----------------|---|--------------------------|---------------------|---------------------|-----------------|-----------------------------------|
| 1. Test         | Ability to explain the basic theories and applications of electron microscopy and spectroscopy techniques, including basic electron optics, electron-beam and specimen interactions, electron imaging techniques and image interpretation; and the basic knowledges and applications of EDS for X-ray microanalysis.  | High                     | Significant         | Moderate            | Basic           | Not even reaching marginal levels |
| 2. Lab reports  | Ability to demonstrate the theoretical understanding gained from lectures to understand and interpret experimental data as well as perform the SEM/TEM experiments; and the evidence of background work done by the students before and after experiments, presentation of results, discussion on the observations and measurements, references, and organization and quality of presentation.  | High                     | Significant         | Moderate            | Basic           | Not even reaching marginal levels |
| 3. Examination  | Ability to explain the electron microscopy (SEM/TEM) principles, including basic electron optics, electron-beam and specimen interactions, electron diffraction, advanced electron imaging techniques and image interpretation; the basic theories of X-Ray Energy Dispersive Spectroscopy (EDS) and its applications for qualitative and quantitative X-ray microanalysis; the fundamentals of the modern electron microscope hardware, including vacuum system, and other basic instrumentations. | High                     | Significant         | Moderate            | Basic           | Not even reaching marginal levels |

### Part III Other Information (more details can be provided separately in the teaching plan)

#### 1. Keyword Syllabus

- This course covers theory and applications of electron microscopy techniques with an emphasis on transmission and scanning electron microscopy (TEM, SEM). Topics include modern electron microscope and instrumentation, electron optics, electron diffraction, imaging techniques, tomography (electron backscatter diffraction, EBSD), and X-ray microanalysis (energy dispersive spectroscopy, EDS), as well as recently developed in situ electron microscopy techniques.
- Hands-on laboratory using the instruments in the CSE advanced microscopy platform (FEI Quanta 450 FE-SEM) and department's SEM (JEOL JSM-5600, FEI Quanta 250) and TEM (JEOL 2100F). The students will gain the knowledge and ability necessary to prepare the samples, operate the instruments and analyze data independently.

#### 2. Reading List

##### 2.1 Compulsory Readings

|    |   |
|----|---|
| 1. | J. Goldstein et al., "Scanning Electron Microscopy and X-Ray Microanalysis" Springer (3rd edition)                        |
| 2. | D.B. Willams and C.B. Carter, "Transmission Electron Microscopy: A Textbook for Materials Science" Springer (2nd edition) |

##### 2.2 Additional Readings

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| 1. | P.J. Goodhew, J. Humphreys and R. Beanland, "Electron Microscopy and Analysis" Taylor & Francis Group 3rd edition |
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